

Notice of Allowability

Application No.

10/659,556

Examiner

Michael P. Stafira

Applicant(s)

VAEZ-IRAVANI, MEHDI

Art Unit

2877

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to amendment filed January 17, 2006.
2. ☒ The allowed claim(s) is/are 1-7 and 10-94.
3. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
 - a) ☐ All b) ☐ Some* c) ☐ None of the:
 1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

* Certified copies not received: _____.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.

THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
5. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
 - (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
 - 1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____.
 - (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____.

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

1. ☐ Notice of References Cited (PTO-892)
2. ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08),
Paper No./Mail Date _____
4. ☐ Examiner's Comment Regarding Requirement for Deposit
of Biological Material
5. ☐ Notice of Informal Patent Application (PTO-152)
6. ☐ Interview Summary (PTO-413),
Paper No./Mail Date _____
7. ☐ Examiner's Amendment/Comment
8. ☒ Examiner's Statement of Reasons for Allowance
9. ☐ Other _____

DETAILED ACTION

Drawings

1. The drawings were received on February 16, 2006. These drawings are approved by the examiner of record.

Allowable Subject Matter

1. Claims 1-7, 10-94 are allowed over the prior art of record.
2. The following is an examiner's statement of reasons for allowance:

After further review and search by the examiner applicant's amendment and remarks dated January 17, 2006 the allowable subject matter are as following:

Regarding claim 1, the prior art fails to disclose or make obvious a surface inspection apparatus suitable for use in detecting anomalies on different types of surfaces having optics comprising optical devices at different azimuthal angles about a line normal to the surface or about a direction corresponding thereto, the devices disposed so that radiation scattered by the surface at different azimuthal angles with respect to the line is directed to different devices without employing a common collecting instrument, and at least one collector substantially in a double dark field arrangement relative to the second beam and having an aperture larger than that of any one of the optical devices collecting radiation scattered by the surface, and in combination with the other recited limitations of claim 1. Claims 2-7, 10-31 are allowed by the virtue of dependency on the allowed claim 1.

Regarding claim 32, the prior art fails to disclose or make obvious a method for detecting anomalies on different types of surfaces by means of an apparatus having optics comprising optical devices at different azimuthal angles about a line normal to the surface or about a direction corresponding thereto, the devices disposed so that radiation scattered by the surface at different azimuthal angles with respect to the line is directed to different devices, and at least one collector having an aperture larger than that of any one of the optical devices and substantially in a double dark field arrangement relative to the second beam collecting causing the source to supply the first and/or second beam to the surface and causing the surface to be scanned by the beam; directing radiation scattered by the surface to the optical devices without employing a common collecting instrument; detecting radiation scattered by the surface and collected by the devices and/or the at least one collector; and determining from the detected radiation anomalies on different types of surfaces, and in combination with the other recited limitations of claim 32. Claims 33-47 are allowed by the virtue of dependency on the allowed claim 32.

Regarding claim 48, the prior art fails to disclose or make obvious a surface inspection apparatus suitable for use in detecting anomalies on different types of surfaces having optics comprising optical devices at different azimuthal angles about a line normal to the surface or about a direction corresponding thereto, the devices disposed so that radiation scattered by the surface at different azimuthal angles with respect to the line is directed to different devices without employing a common collecting instrument, and at least one collector substantially in a double dark field arrangement relative to the second beam and having an aperture larger than that of any one of the optical devices collecting radiation scattered by the surface, and in combination

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with the other recited limitations of claim 48. Claims 49-78 are allowed by the virtue of dependency on the allowed claim 48.

Regarding claim 79, the prior art fails to disclose or make obvious a method of detecting anomalies on different types of surfaces by means of an apparatus having optics comprising optical devices at different azimuthal angles about a line normal to the surface or about a direction corresponding thereto, the devices disposed so that radiation scattered by the surface at different azimuthal angles with respect to the line is directed to different devices, and at least one collector having an aperture larger than that of any one of the optical devices and substantially in a double dark field arrangement relative to the second beam collecting and focusing radiation scattered by the surface; causing the source to supply the first or second beam to the surface and causing the surface to be scanned by the beam; directing radiation scattered by the surface to the optical devices without employing a common collecting instrument; detecting radiation scattered by the surface and collected by the devices and/or the at least one collector; and determining from the detected radiation anomalies on different types of surfaces, and in combination with the other recited limitations of claim 79. Claims 80-94 are allowed by the virtue of dependency on the allowed claim 79.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

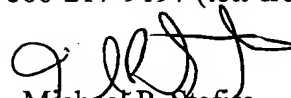
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Any inquiry concerning this communication or earlier communications from the examiner should be directed to Michael P. Stafira whose telephone number is 571-272-2430.

The examiner can normally be reached on 4/10 Schedule Mon.-Thurs..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory Toatley can be reached on 571-272-2800 ext. 77. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).


Michael P. Stafira
Primary Examiner
Art Unit 2877

April 24, 2006